

TORMPTO-1449 (Coll.)

ALLEN DOCKLEBEN
1401339648SERIAL NUMBER
09/829,438LIST OF PATENTS AND PUBLICATIONS
FOR APPLICANT'S INFORMATION
STATEMENTAPPLICANT
Yoel ARIEL, et al.FILING DATE
April 9, 2001 GROUP PART UNIT
2877

U.S. PATENT DOCUMENTS

Examiner's Initials	DOCUMENT NO.	DATE	NAME	CLASS	SUB	FILING DATE
ab	AA 5,969,858	Oct 1999	Ishiwata, et al.	359	386	
	AB 5,969,853	OCT 1999	Takaoaka	359	370	
	AC 5,936,253	Aug 1999	Sugaya	250	548	
	AD 5,870,191	Feb 1999	Shirley, et al.	345	356	
	AE 5,814,815	Sep 1998	Matsumoto, et al.	250	311	
	AF 5,751,475	May 1998	Ishiwata, et al.	359	387	
	AG 5,619,372	Apr 1997	Hellmuth, et al.	359	389	
	AH 5,600,440	Feb 1997	Bendall	356	345	

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Examiner's Initials	DOCUMENT NO.	DATE	COUNTRY	CLASS	SUB	TRANSLATION
ab	AI JP 9230247	9/1997	Japan			
	AI JP 9129629	7/1997	Japan			
	AK JP 8084936	4/1996	Japan			

OTHER AREA OF EXAMINER'S PERTINENT PAPERS

M Photon D W "General Methods for Generating Phase-Shifting Interferometry Algorithms," Applied Optics, Vol. 36, 8098, 1997.

AM Pluta M "Stray-light Problem in Phase Contrast Microscopy or Toward Highly Sensitive Phase Contrast Devices: A review," Optical engineering, Vol. 32, 3169, 1993.

EXAMINER

 DATE CONSIDERED 11/16/01

EXAMINER Initial reference considered, whether or not citation is in conformance with AIA 35 U.S.C. 102(e). Draw line through citation if not in conformance and not considered. Includes copy of this form with next communication to applicant.

FORM PTO-1449 (Rev. 1)

ATTY DOCKET NO.

14013596-8

SERIAL NUMBER

09/829,435

**LIST OF PATENTS AND PUBLICATIONS
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STATEMENT**

APPLICANT
Yoel ARIEL et al.

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GROUP ARTICLE

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	DOCUMENT NO.	DATE	NAMES	CLASS	SUB.	FILING DATE
AK	5,159,474	Oct. 1992	Franke, et al	359	29	
AB	5,777,736	Jul. 1998	Horton	256	346	
AC	4,653,921	Mar. 1987	Kwon	256	353	

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AK Golden J. L. "Zernike Test: Analytical Aspects" "Applied Optics", Vol. 16, 205 (1977).

AK Bruning J.H. et al. "Digital Wavefront Measuring Interferometry for Testing Optical Surfaces and Lenses" "Applied Optics", Vol. 13, 2693 (1974).

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TORXPTO-1449 (Colb)

VALY DOKEENO

SERIAL NUMBER

14013396-8

09 829 435

**LIST OF PATENTS AND PUBLICATIONS
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APPLICANT
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Examiner's Initials	DOCUMENT NO.	DATE	NAME	CLASS	SUB.	FILING DATE
AK	5,421,303	Nov 1995	Ari et al	356	257	
AB	5,446,540	Aug 1995	Lin	356	245	
AC	5,235,587	Apr 1993	Bearden et al	369	106	
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AK Creath K, "Phase Measurement Interferometry Techniques", Progress in Optics XXVI, 348 (1988).

AK Greivenkamp J.E., "Generalized Data Reduction for heterodyne Interferometry", Optical Engineering, Vol. 23, 35 (1984).

M Morgan C.J., "Least Squares Estimation in Phase-Measurement Interferometry", Optics Letters, Vol. 7, 368 (1982).

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609. Draw line through citation if not in conformance and not considered. Include
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